

Application. No. 10/604,323

Amendment dated December 14, 2005

Amendment made in response to Notice of Allowance dated September 14, 2005

**Amendments to Claims**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries; and  
passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer.
  
2. (original) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a memory cell.
  
3. (original) The barrier stack of claim 2 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.
  
4. (previously presented) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a plurality of memory cells arranged in a series architecture.
  
5. (original) The barrier stack of claim 4 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.

Application No. 10/604,323

Amendment dated December 14, 2005

Amendment made in response to Notice of Allowance dated September 14, 2005

6. (original) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a ferroelectric memory cell.

7. (original) The barrier stack of claim 6 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.

8. (previously presented) The barrier stack of claim 1 serves as a barrier for capacitor over plug structure of a plurality of ferroelectric memory cells arranged in a series architecture.

9. (original) The barrier stack of claim 8 wherein the capacitor over plug structure includes a plug having a step over an ILD layer.

10. (cancelled)

11. (cancelled)

12. (cancelled)

13. (cancelled)

14. (cancelled)

15. (cancelled)

16. (cancelled)

17. (cancelled)

Application. No. 10/604,323

Amendment dated December 14, 2005

Amendment made in response to Notice of Allowance dated September 14, 2005

18. (currently amended) The barrier stack of claim 1, 2 or 6 wherein the passivating elements comprises oxygen .

19. (previously presented) The barrier stack of claim 18 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

20. (previously presented) The barrier stack of claim 19 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

21. (currently amended) The barrier stack of claim 18 19 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

22. (cancelled)

23. (currently amended) The barrier stack of claim 1, 2 or 6 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

24. (previously presented) The barrier stack of claim 23 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

25. (currently amended) The barrier stack of claim 1, 2 or 6 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

Application. No. 10/604,323

Amendment dated December 14, 2005

Amendment made in response to Notice of Allowance dated September 14, 2005

26. (currently amended) The barrier stack of claim 1, 2 or 6 23 wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

27. (previously presented) The barrier stack of claim 26 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and  
the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

28. (previously presented) The barrier stack of claim 27 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

29. (previously presented) The barrier stack of claim 26 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

30. (currently amended) The barrier stack of claim 1, 2 or 6 further comprises an upper barrier layer disposed above the second sub-barrier layer, the upper barrier layer comprises a conductive oxide.

31 (previously presented) The barrier stack of claim 30 wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

32. (previously presented) The barrier stack of claim 30 wherein the passivating elements comprises oxygen.

33. (previously presented) The barrier stack of claim 30 wherein:  
the first sub-barrier material comprises Ir, Ru, Rh, Pd, Hf or a combination thereof; and

the second sub-barrier material comprises Ir, Ru, Rh, Pd, Hf, a conductive oxide or a combination thereof.

34. (previously presented) The barrier stack of claim 30 wherein the grain boundaries of the first and second sub-barrier layers are mismatched.

35. (currently amended) The barrier stack of claim 31 30 wherein the grain boundaries of the upper barrier and second sub-barrier layers are mismatched.

36. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries; and  
passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer, wherein the passivating elements comprises a size greater than the grain boundaries of the first sub-barrier layer.

37. (previously presented) A barrier stack comprising:  
a first sub-barrier layer, the first sub-barrier layer comprises a first sub-barrier conductive barrier material, the first sub-barrier layer includes grain boundaries;  
a second sub-barrier layer disposed above the first sub-barrier layer, the second sub-barrier layer comprises a second sub-barrier conductive barrier material, the second sub-barrier layer includes grain boundaries;  
wherein grain boundaries of the first and second sub-barrier layers are mismatched; and

Application No. 10/604,323

Amendment dated December 14, 2005

Amendment made in response to Notice of Allowance dated September 14, 2005

passivating elements are provided to passivate grain boundaries on an upper surface of the first sub-barrier layer.